

ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18

Stylesheet Version v18.0

Title of Invention

Method for forming silicon dioxide film using siloxane

Application Number : 10/782094
Confirmation Number: 4756
First Named Applicant: Jae-Eun Park
Attorney Docket Number: SAM-0483
Art Unit:
Examiner:
Search string: (20040096582).pn



US Published Applications

Note: Applicant is not required to submit a paper copy of cited US Published Applications

init	Cite.No.	Pub. No.	Date	Applicant	Kind	Class	Subclass
	1	20040096582	2004-05-20	Wang, et al.			

Remarks

Note: Remarks are not for responding to an office action.

Part 1 of 1.

Signature

Examiner Name	Date